

IN THE CLAIMS

Please amend the claims as follows:

1-24. (Canceled).

25. (Currently Amended) A tool holder device for supporting at least one tool configured to collaborate with an edge of at least one substrate, ~~positioned on edge~~, the device comprising:

a rotary support configured to receive the at least one tool, and to move ~~make the at least one tool move~~ translationally along a vertical beam and rotationally relative to the at least one substrate[[,]];

the vertical beam provided with the rotary support and with a linear guidance element extending at least partially over a height of the vertical beam, the linear guidance element being configured to prevent the rotary support from rotating when the rotary support is moved translationally, wherein it being possible for

the at least one substrate ~~to be~~ is moved translationally relative to the at least one tool supported by the rotary support, as the at least one tool is operating in a predetermined position, wherein and

collaboration between the at least one tool and the at least one substrate occurs with or without contact relative to an edge face of the at least one substrate.

26. (Currently Amended) The device as claimed in claim 25, wherein the ~~device~~ rotational support is controlled via a control loop to ensure precise positioning of the at least one tool relative to the at least one substrate.

27. (Currently Amended) The device as claimed in claim 26, further comprising:

means for compensating for a position of the at least one substrate; and
at least one position sensor,
wherein the means for compensating and the at least one position sensor are
~~configured to be~~ associated with the at least one tool.

28. (Previously Presented) The device as claimed in claim 25, wherein the at least one tool comprises means for measuring, machining, shaping or treating the at least one substrate.

29. (Previously Presented) The device as claimed in claim 25, wherein the at least one tool comprises means for applying and bonding an interlayer to all or part of a periphery and to the edge faces of at least two substrates facing each other.

30. (Previously Presented) The device as claimed in claim 29, wherein the means for applying and bonding comprises at least two press rollers each configured to press against one of the edge faces of the two substrates, the two process rollers being control-loop controlled independently.

31. (Previously Presented) The device as claimed in claim 27, wherein the means for compensating for the position of a substrate and a position sensor are associated with each of the press rollers respectively.

32. (Currently Amended) The device as claimed in claim 25, ~~further comprising a rotary support on which~~ wherein the at least one tool is fixed to the rotary support and a linear

~~guidance element with which the rotary support collaborates, the support being prevented from rotating when moved translationally by the linear guidance element.~~

33. (Canceled).

34. (Currently Amended) The device as claimed in claim 25, comprising a first tool configured to move translationally ~~and/or~~ or rotationally, and a second tool arranged fixedly and configured to operate while the at least one substrate is moving translationally.

35. (Currently Amended) The device as claimed in claim 26, wherein the rotational and translational movements of the at least one tool and the control loop control of the ~~device~~ rotational support are controlled by a numerical control.

36. (Previously Presented) An installation comprising:
a tool holder device as claimed in claim 25, and
at least one module for progressing, holding, and positioning the at least one substrate in X, Y, Z directions of space facing the tool holder device.

37. (Previously Presented) The installation as claimed in claim 36, wherein the at least one module for progressing, holding, and positioning comprises a fixed chassis that comprises a substantially vertical stand, means for holding and positioning a substrate against the stand in the X and Y directions, and means for holding and positioning the substrate in the Z-direction.

38. (Currently Amended) The installation as claimed in claim 37, wherein the means for holding and positioning the substrate against the stand in the X and Y directions and the means for holding and positioning the substrate in the Z-direction is controlled through a control loop.

39. (Currently Amended) The installation as claimed in claim 36, wherein the at least one module for progressing, holding, and positioning comprises a fixed chassis and a moving chassis, ~~these~~ the fixed chassis and the moving chassis collaborating with one another to each support at least one substrate, the substrates being placed facing each other and positioned relative to one another with a given separation.

40. (Previously Presented) The installation as claimed in claim 39, wherein the fixed chassis and the moving chassis are open in their upper part so as to support substrates of any dimensions.

41. (Previously Presented) The installation as claimed in claim 39, wherein the moving chassis comprises means for positioning, in the Z-direction, the substrate resting on the moving chassis so as to obtain a desired separation between the two substrates.

42. (Previously Presented) The installation as claimed in claim 39, wherein the moving chassis comprises means for holding and positioning, in the X-direction, the two substrates resting on the fixed and moving chassis, the means for holding and positioning configured to be moved in the Z-direction independently of the moving chassis.

43. (Currently Amended) The installation as claimed in claim 36, wherein the at least one module comprises means for transferring a substrate supported by ~~[[the]]~~ a fixed chassis to ~~[[the]]~~ a moving chassis.

44. (Currently Amended) The installation as claimed in claim 37, wherein the means for holding and positioning ~~[[a]]~~ the substrate against the stand in the X and Y directions and the means for holding and positioning the substrate in the Z-direction substrate ~~comprises~~ comprise conveyor belts and suction means for holding the substrate tightly against the conveyor belts.

45. (Previously Presented) The installation as claimed in claim 44, further comprising an additional high-performance suction device to generate a tangential holding force holding the substrate at the end of the at least one module.

46. (Currently Amended) The installation as claimed in claim 36, wherein a holding system using suction cups is provided, associated with the at least one module, ~~for routing to route~~, from the at least one module to an adjacent support element, a substrate which, in the X-direction, has a dimension substantially equivalent to or smaller than a space separating the module from the support element adjacent to the at least one module.

47. (Previously Presented) The installation as claimed in claim 36, further comprising plural modules for progressing, holding, and positioning substrates, which may or may not be electronically coupled depending on lengths of the substrates.

48. (Currently Amended) The installation as claimed in claim 36, wherein the at least one module for progressing, holding, and positioning constitutes a module for preassembling ~~and/or~~ or assembling an insulating glazing comprising at least two glass substrates and an interlayer secured to all or part of a periphery of the at least two glass substrates.